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Docket No.: 0160-0193-0 PCT

COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

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RE: Application Serial No.: 09/463,961
Applicants: Hiroshi IKEDA, ET AL.
Filing Date: May 25, 2000
For: METHOD AND APPARATUS FOR PROCESSING
EXHAUST GAS OF SEMICONDUCTOR FABRICATION
Group Art Unit: 1754
Examiner: VANOY, T.

"RESPONSE UNDER 37 CFR 1.116-
EXPEDITED PROCEDURE EXAMINING
GROUP 1754"

SIR:

Attached hereto for filing are the following papers:

REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION

Attachments:

JP 5-80243

English-language translation of JP 5-80243, column 3, line 23 to column 4, line 1

Information Disclosure Statement/Form PTO-1449/Cited References (3)

Request for Extension of Time (two month)

Our check in the amount of \$580.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.

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